

SUBSTRATE PROCESSING SYSTEM AND SUBSTRATE PROCESSING METHOD

ABSTRACT

The disclosed substrate processing system includes a vacuum transfer module, a controller, a plurality of process modules, an aligner, a memory, and an identification module. The aligner has a stage and an optical sensor. The stage is configured to have a ring member placed thereon. The optical sensor is configured to detect a shape of the ring member placed on the stage. The memory includes a table storing feature information indicating a feature of each of a plurality of ring members, the feature information being associated with an identifier of each of the plurality of process modules. The identification module extracts the feature information of the ring member from the shape of the ring member detected by the optical sensor, and refers to the table of the memory to identify a process module among the plurality of process modules to which the ring member is to be transferred, from the identifier associated with the feature information.

[Fig. 4]